507745249 02/13/2023

PATENT ASSIGNMENT COVER SHEET

Electronic Version v1.1 Stylesheet Version v1.2 EPAS ID: PAT7792397

SUBMISSION TYPE:	NEW ASSIGNMENT
NATURE OF CONVEYANCE:	ASSIGNMENT

CONVEYING PARTY DATA

Name	Execution Date
VARUN SHARMA	09/02/2021
DANIELE CHIAPPE	08/26/2021
EVA TOIS	08/25/2021
VIRAJ MADHIWALA	08/25/2021
MARKO TUOMINEN	09/03/2021
CHARLES DEZELAH	08/26/2021
MICHAEL GIVENS	08/25/2021
TOM BLOMBERG	02/08/2023

RECEIVING PARTY DATA

Name:	ASM IP HOLDING B.V.
Street Address:	VERSTERKERSTRAAT 8
City:	ALMERE
State/Country:	NETHERLANDS
Postal Code:	1322 AP

PROPERTY NUMBERS Total: 1

Property Type	Number
Application Number:	17472981

CORRESPONDENCE DATA

Fax Number: (602)470-2434

Correspondence will be sent to the e-mail address first; if that is unsuccessful, it will be sent

using a fax number, if provided; if that is unsuccessful, it will be sent via US Mail.

Phone: 6024705707

Email: asia.gul@asm.com
Correspondent Name: PATRICK LEE

Address Line 1: 3440 E. UNIVERSITY DRIVE Address Line 4: PHOENIX, ARIZONA 85034

ATTORNEY DOCKET NUMBER:	100175US02
NAME OF SUBMITTER:	ASIA GUL
SIGNATURE:	/Asia Gul/

PATENT REEL: 062669 FRAME: 0510

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DATE SIGNED:	02/13/2023
Total Attachments: 9	
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PATENT REEL: 062669 FRAME: 0511 Application Serial No.: 17/472,981 Docket No.: 100175US02

Filing Date: September 13, 2021

Title: SILICON OXIDE DEPOSITION METHOD

ASSIGNMENT

WHEREAS, Varun Sharma, a citizen of India and a resident of Helsinki, FI; Daniele Chiappe, a citizen of Italy and a resident of Espoo, FI; Eva Tois, a citizen of Finland and a resident of Espoo, FI; Viraj Madhiwala, a citizen of India and a resident of Helsinki, FI; Marko Tuominen, a citizen of Finland and a resident of Helsinki, FI; Charles Dezelah, a citizen of United States of America and a resident of Helsinki, FI; Michael Givens, a citizen of United States of America and a resident of Oud-Heverlee, BE; Tom Blomberg, a citizen of Finland and a resident of Vantaa, FI;

(collectively, "WE" or "ASSIGNOR") have conceived of one or more processes, methods, machines, articles of manufacture, designs, compositions of matter, inventions, discoveries or new or useful improvements relating to SILICON OXIDE DEPOSITION METHOD (collectively, the "INVENTIONS") for which WE have executed and/or may execute one or more patent applications therefore; and

WHEREAS, ASM IP HOLDING B.V. (hereinafter "ASSIGNEE"), a corporation having a place of business at Versterkerstraat 8, Almere, 1322 AP, Netherlands, desires to acquire or otherwise obtain the entire right, title, and interest in and to said INVENTIONS, including all patent applications therefore, and all patents that have granted or may be granted hereafter thereon, including, but not limited to, those identified below.

NOW, THEREFORE, for good and valuable consideration, the receipt of which is hereby acknowledged, WE do hereby acknowledge that WE have sold, assigned, conveyed and transferred, and by these presents do hereby sell, assign, convey and transfer, unto ASSIGNEE, its successors, its legal representatives and its assigns, the entire right, title, and interest throughout the world in and to said INVENTIONS, including all patent applications therefore that may have been filed or may be filed hereafter for said INVENTIONS (including but not limited Application No(s). 17/472,981, filed on September 13, 2021, as Docket No. 100175US02 (and do hereby authorize ASSIGNEE and its representative to hereafter add herein such application number(s) and/or filing date(s) when known)) and all rights of priority under International Conventions, Treaties, and Agreements, all utility applications, national phase applications, utility model applications, divisional applications, renewal applications, continuation applications, validation applications and design applications thereof, and all issued patents which may have granted or may be granted hereafter thereon and all reissues, renewals, reexaminations, and extensions to any of the foregoing and all patents issuing thereon;

AND WE DO HEREBY authorize and request any Official of any country or countries whose duty it is to issue patents on applications or registrations, to issue all patents for said

Application Serial No.:Filing Date:	Docket No.: 100175US02
Filing Date: Title: SILICON OXIDE DEPOSITION METH	OD
INVENTIONS to ASSIGNEE, its successors, it accordance with the terms of this instrument;	ts legal representatives, and its assigns, in
legal representatives, and its assigns all claims to relating to any violation(s) of any of the rights a prior to the date of assignment to said ASSIGN	assigned hereby that have or may have accrued EE, or may accrue hereafter, including, but not ect, recover and retain damages and any ongoing ntitled, or form any settlement or agreement
* *	tives, and its assigns, any facts known to us in any legal proceeding, sign all lawful papers, all rightful declarations and/or oaths, and provide accessors, its legal representatives, and its assigns,
EXECUTED as of the date(s) below by ASSIG	NOR:
Varun Sharma	02, Sopkinder, 2021 Date
Signature	Date
Daniele Chiappe	
Signature	Date
Eva Tois	
Signature	Date
Viraj Madhiwala	
Signature	Date

INVENTIONS to ASSIGNEE, its successors, its legal representatives, and its assigns, in accordance with the terms of this instrument; AND WE DO HEREBY sell, assign, transfer, and convey to said ASSIGNEE, its successors, its legal representatives, and its assigns all claims for damages and all remedies arising out of or relating to any violation(s) of any of the rights assigned hereby that have or may have accrued prior to the date of assignment to said ASSIGNEE, or may accrue hereafter, including, but not limited to the right to sue for, seek, obtain, collect, recover and retain damages and any ongoing or prospective royalties to which WE may be entitled, or form any settlement or agreement related to any of said patents before or after issuance; AND WE HEREBY covenant and agree that WE will communicate promptly to said ASSIGNEE, its successors, its legal representatives, and its assigns, any facts known to us respecting said INVENTIONS, and will testify in any legal proceeding, sign all lawful papers, execute all applications and certificates, make all rightful declarations and/or oaths, and provide all lawful assistance to said ASSIGNEE, its successors, its legal representatives, and its assigns, to obtain and enforce patent protection for said INVENTIONS in all countries. EXECUTED as of the date(s) below by ASSIGNOR: Varun Sharma Signature Date Date Viraj Madhiwala Signature Date Date	Filing Date: Title: SILICON OXIDE DEPOSITION METHOD	
legal representatives, and its assigns all claims for damages and all remedies arising out of or relating to any violation(s) of any of the rights assigned hereby that have or may have accrued prior to the date of assignment to said ASSIGNEE, or may accrue hereafter, including, but not limited to the right to sue for, seek, obtain, collect, recover and retain damages and any ongoing or prospective royalties to which WE may be entitled, or form any settlement or agreement related to any of said patents before or after issuance; AND WE HEREBY covenant and agree that WE will communicate promptly to said ASSIGNEE, its successors, its legal representatives, and its assigns, any facts known to us respecting said INVENTIONS, and will testify in any legal proceeding, sign all lawful papers, execute all applications and certificates, make all rightful declarations and/or oaths, and provide all lawful assistance to said ASSIGNEE, its successors, its legal representatives, and its assigns, to obtain and enforce patent protection for said INVENTIONS in all countries. EXECUTED as of the date(s) below by ASSIGNOR: Varun Sharma Signature Date Date Viraj Madhiwala		presentatives, and its assigns, in
ASSIGNEE, its successors, its legal representatives, and its assigns, any facts known to us respecting said INVENTIONS, and will testify in any legal proceeding, sign all lawful papers, execute all applications and certificates, make all rightful declarations and/or oaths, and provide all lawful assistance to said ASSIGNEE, its successors, its legal representatives, and its assigns, to obtain and enforce patent protection for said INVENTIONS in all countries. EXECUTED as of the date(s) below by ASSIGNOR: Varun Sharma Date Date Eva Tois Signature Date Date Viraj Madhiwala	legal representatives, and its assigns all claims for damage relating to any violation(s) of any of the rights assigned he prior to the date of assignment to said ASSIGNEE, or me limited to the right to sue for, seek, obtain, collect, recover or prospective royalties to which WE may be entitled, or	tes and all remedies arising out of or tereby that have or may have accrued by accrue hereafter, including, but not er and retain damages and any ongoing
Varun Sharma Signature Date Date Z6/08/2071 Signature Date Eva Tois Signature Date Viraj Madhiwala	ASSIGNEE, its successors, its legal representatives, and respecting said INVENTIONS, and will testify in any leg execute all applications and certificates, make all rightful all lawful assistance to said ASSIGNEE, its successors, it	its assigns, any facts known to us all proceeding, sign all lawful papers, declarations and/or oaths, and provide is legal representatives, and its assigns,
Signature Date Daniele Chiappe 26/08/2021 Signature Date Eva Tois Signature Date Date Date	EXECUTED as of the date(s) below by ASSIGNOR:	
Daniele Chiappe 26/08/2021 Signature Date	Varun Sharma	
Signature Date Eva Tois Signature Date Viraj Madhiwala	Signature	Date
Eva Tois Signature Date Viraj Madhiwala	Daniele Chiappe	**************************************
Eva Tois Signature Date Viraj Madhiwala	South Outer	26/08/2021
Signature Date Viraj Madhiwala	Signature	
Viraj Madhiwala	Eva Tois	
	Signature	Date
Signature Date	Viraj Madhiwala	
	Signature	Date

Application Serial No.:

Docket No.: 100175US02

Application Serial No.:	Docket No.: 100175US02
Filing Date: Title: SILICON OXIDE DEPOSITION METHOD	
INVENTIONS to ASSIGNEE, its successors, its le accordance with the terms of this instrument;	gal representatives, and its assigns, in
AND WE DO HEREBY sell, assign, transfer, and of legal representatives, and its assigns all claims for or relating to any violation(s) of any of the rights assign prior to the date of assignment to said ASSIGNEE, limited to the right to sue for, seek, obtain, collect, or prospective royalties to which WE may be entitled to any of said patents before or after issuance.	damages and all remedies arising out of or gned hereby that have or may have accrued or may accrue hereafter, including, but not recover and retain damages and any ongoing ed, or form any settlement or agreement
AND WE HEREBY covenant and agree that WE was ASSIGNEE, its successors, its legal representatives respecting said INVENTIONS, and will testify in a execute all applications and certificates, make all rial lawful assistance to said ASSIGNEE, its success to obtain and enforce patent protection for said INV	s, and its assigns, any facts known to us any legal proceeding, sign all lawful papers, ghtful declarations and/or oaths, and provide sors, its legal representatives, and its assigns,
EXECUTED as of the date(s) below by ASSIGNO	R:
Varun Sharma	
Signature	Date
Daniele Chiappe	
Signature	Date
Eva Tois	
Eua Tais	25-Aug-2021
Signature	Date
Viraj Madhiwala	
Signature	Date

Page 2 of 3

Application Serial No.:	Docket No.: 100175US02
Filing Date: Title: SILICON OXIDE DEPOSITION METI	-dod
INVENTIONS to ASSIGNEE, its successors, accordance with the terms of this instrument;	its legal representatives, and its assigns, in
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legal representatives, and its assigns all claims relating to any violation(s) of any of the rights prior to the date of assignment to said ASSIGN	-
execute all applications and certificates, make	atives, and its assigns, any facts known to us y in any legal proceeding, sign all lawful papers, all rightful declarations and/or oaths, and provide accessors, its legal representatives, and its assigns,
EXECUTED as of the date(s) below by ASSIG	GNOR:
Varun Sharma	
Signature	Date
Daniele Chiappe	
Signature	Date
Eva Tois	
Signature	Date
Viraj Madhiwala	
Quelli	25-98-2021
Signature	Date

Filing Date: Title: SILICON OXIDE DEPOSITION METHOD	Docket No.; 1001/3030.
Marko Tuominen	3/9/2021
Signature	Date
Charles Dezelah	
Signature	Date
Michael Givens	
Signature	Date
Tom Blomberg	
Signature	Date

Application Serial No.: Filing Date: Title: SILICON OXIDE DEPOSITION METHOD	Docket No.: 100175US0
Marko Tuominen	
Signature	Date
Charles Dezelah Signature Michael Givens	$\frac{8/2C/2o21}{\text{Date}}$
Signature Tom Blomberg	Date
Signature	Date

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Marko Tuominen	
	April Dangar and Seglet Salaries
Charles Dezelah	Date Date
Signature	Date
Michael Givens	75-AU6-2021
Signature	Date
Tom Blomberg	And the property of the analysis of the property of the analysis of the second of the
Signature	Date

Application Serial No.: Filing Date: Title: SILICON OXIDE DEPOSITION METHOD	Docket No.: 100175US02
Marko Tuominen	
Signature	Date
Charles Dezelah	
Signature	Date
Michael Givens	
Signature	Date
Tom Blomberg	00-604-2023
Signature	Date

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